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P2114A IN A Structural Analysis of Graphene and a-IGZO TFTs under the Influence of Thermal Stress

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P2115A-LN RF magnetron sputtering growth and characterization of ZnMgAlO films with UV energy band gap

<u>Hoang Ba Cuong</u>, Jang-Ho Park, Nae-Sang Yoon, Min-Sung Kim, Byung-Teak Lee Chonnam National University

P2116A-LN The characteristics of ZnO; Al thin film using RF-Magnetron sputtering

<u>Bum-Suk Lee</u>, Young-Hee Joo, Jong-Chang Woo, <u>Chang-Il Kim</u> School of Electrical And Electronics Engineering, Chung-Ang University

P2117A-LN DC sputtering of Mo/Cu multilayers for seed layers in high aspect ratio vias

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P2118A-LN Fabrication and Evaluation of $BaZr_{0.1}Ce_{0.7}Y_{0.1}Yb_{0.1}O_3$. (BZCYYb) thin films by e-beam vapor deposition for IT-SOFC applications

Byung Geun Lee, Young Sun Hong, Ngoc Thi Quynh Nguyen, Hyon Hee Yoon Gachon University, Kyungwon University

P3099A LN Development of nanobio-interfaces using microplasma technology

<u>Shigeru Kurosawa</u>, Hidenobu Aizawa, Yousuke Iimura, Yasushi Sato Research Institute For Environmental Management Technology, Japan

P2119C-LN Oxidation of CrAlMgSiN thin films deposited by cathodic arc plasma deposition

Withdrawn Yeon Sang Hwang, Chun Yu Xu, Sung Bin Won, Dong Bok Lee Sungkyunkwan University